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TRANSLATION FROM JAPANESE

- (19) JAPANESE PATENT OFFICE (JP)
- (12) Official Gazette for Unexamined Utility Model Applications (U)
- (11) Unexamined Utility Model No. 63-84866
- (43) Disclosure Date: Jun. 3, 1988

Internal Office		
(51)	<u>Int. Cl.⁴:</u>	<u>Classification Symbols:</u>
		<u>Registration Nos.:</u>
	H01J 37/28	Z-7129-5C
	G01B 15/00	B-8304-2F
	H01J 37/20	D-7129-5C
	H01L 21/66	7168-5F

Request for Examination: Not filed

(Total of 2 pages [in original])

(54) Title of the Invention: **SEM type surface inspection apparatus**

- (21) Application No.: 61-179904
- (22) Filing Date: Nov. 21, 1986
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(57) Claims

(1) SEM type surface inspection apparatus comprising: a scanning electron microscope; and a load-lock chamber situated adjacently to the lens body of said scanning

electron microscope and accommodating a cassette housing a multitude of wafers to be transported into said lens body.

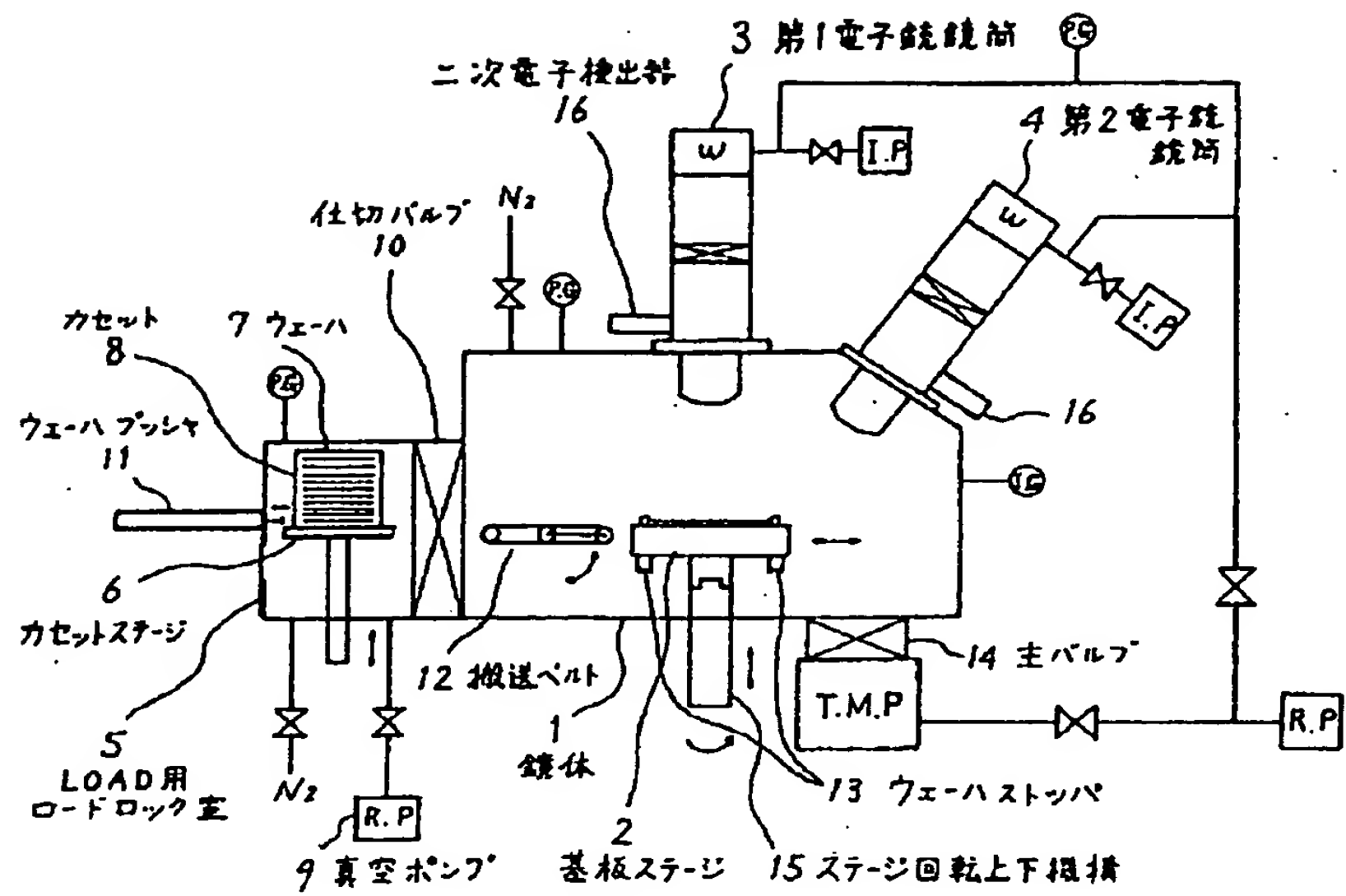
(2) SEM type surface inspection apparatus according to claim 1 wherein said scanning electron microscope mirror body comprises a plurality of electron gun lens barrels.

(3) SEM type surface inspection apparatus according to claim 2 wherein one of said electron gun lens barrels is an electron gun lens barrel for length measurement use.

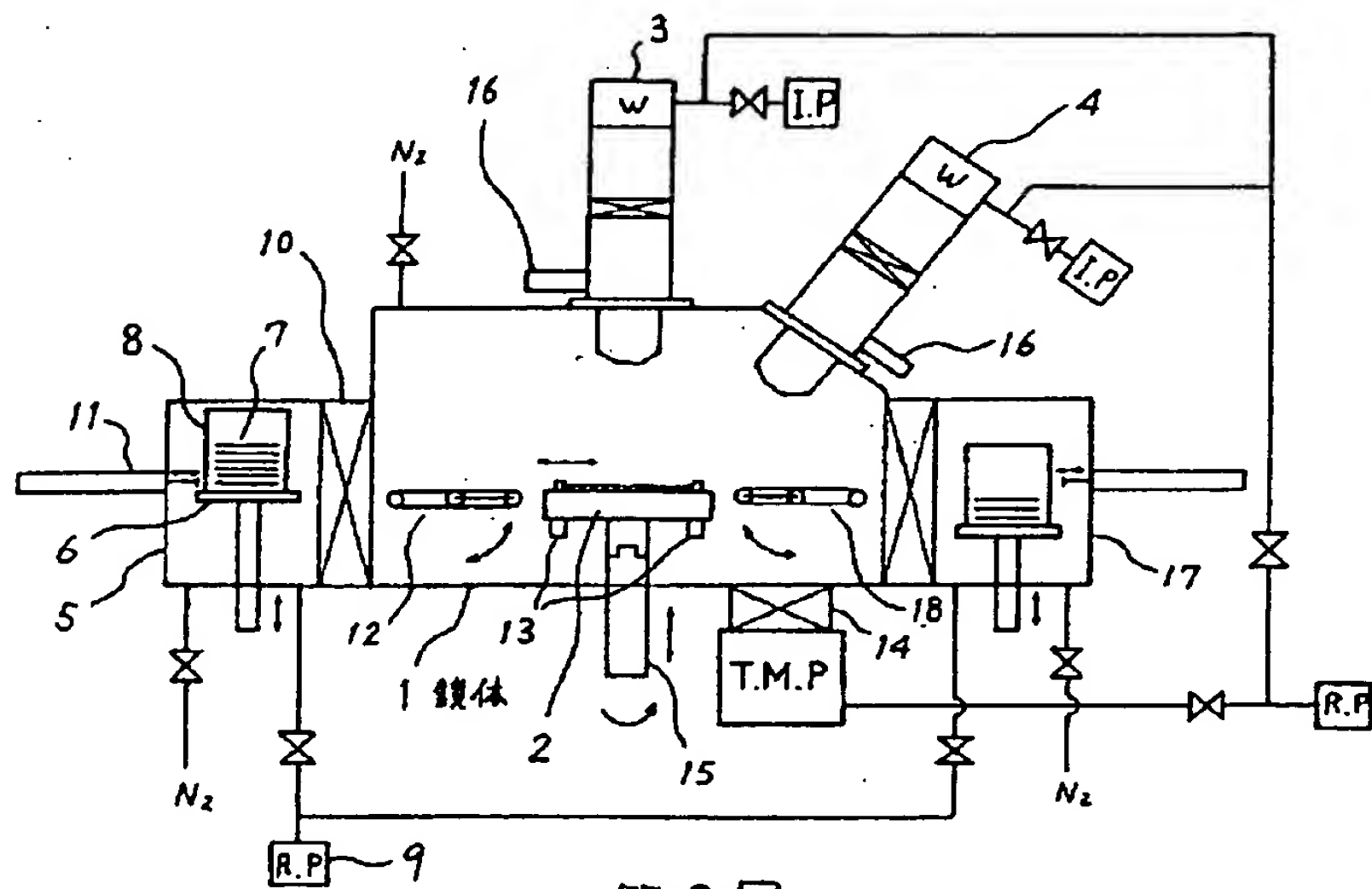
Brief Description of the Drawings

Fig. 1 is a construction diagram showing a first embodiment of the invention; and Fig. 2 is a construction diagram showing a second embodiment of the invention.

1: lens body (chamber); 2: substrate stage; 3: first electron gun lens barrel; 4: second electron gun lens barrel; 5: LOAD load-lock chamber; 6: cassette stage; 7: wafer; 8: cassette; 9: vacuum pump; 10: gate valve; 11: wafer pusher; 12: conveyor belt; 13: wafer stopper; 14: main valve; 15: stage rotating/elevating mechanism; 16: second electron detector; 17: UN LOAD load-lock chamber; 18: conveyor belt.



第1図



第2図

公開実用 昭和63- 84866

⑩ 日本国特許庁(JP)

⑪ 実用新案出願公開

⑫ 公開実用新案公報(U) 昭63- 84866

⑬ Int. Cl. *

識別記号

庁内整理番号

⑭ 公開 昭和63年(1988)6月3日

H 01 J 37/28
G 01 B 15/00
H 01 J 37/20
H 01 L 21/66

Z-7129-5C
B-8304-2F
D-7129-5C
7168-5F

審査請求 未請求 (全 頁)

⑮ 考案の名称 SEM型の外観検査装置

⑯ 実 願 昭61-179904

⑰ 出 願 昭61(1986)11月21日

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